

Electronic Patent Application Fee Transmittal

Application Number:	10821310				
Filing Date:	08-Apr-2004				
Title of Invention:	Apparatus for controlling gas flow in a semiconductor substrate processing chamber				
First Named Inventor/Applicant Name:	Kallol Bera				
Filer:	Keith Patrick Taboada				
Attorney Docket Number:	8549/ETCH/DRIE/JB1				
Filed as Large Entity					
Utility Filing Fees					
Description		Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:					
Pages:					
Claims:					
Miscellaneous-Filing:					
Petition:					
Patent-Appeals-and-Interference:					
Filing a brief in support of an appeal		1402	1	500	500
Post-Allowance-and-Post-Issuance:					
Extension-of-Time:					

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Total in USD (\$)				500